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ABSTRACT OF THE DISCLOSURE

Instead of directly performing defect inspection using a master information carrier, an inspection substrate is prepared to then bring the master information carrier in close contact therewith, to thereby transfer a defect on the master information carrier to the inspection substrate, thus indirectly inspecting any defect of the master information carrier on the inspection substrate. Defect inspection is performed on the first-state inspection substrate before close contacting, so that a defect inspection result on the second-state inspection substrate after close contacting and that on the first-state inspection substrate are compared to each other.

Figure 1